

New Facility

Nano Science and Engineering Platform @ HKUST

- ❖ A central facility supported by UGC Special Equipment Grant (SEG_HKUST08)
- ❖ In addition to serving HKUST, users from other institutions, laboratories and industries are also welcome
- ❖ Suitable for fabrication, manipulation and in-situ modification of nanostructures



Raith e_LiNE

- Electron beam lithography with sub 20nm resolution
- 100 x 100 mm laser interferometer stage
- E-beam induced deposition and etching
- Nano probing and electrical measurements

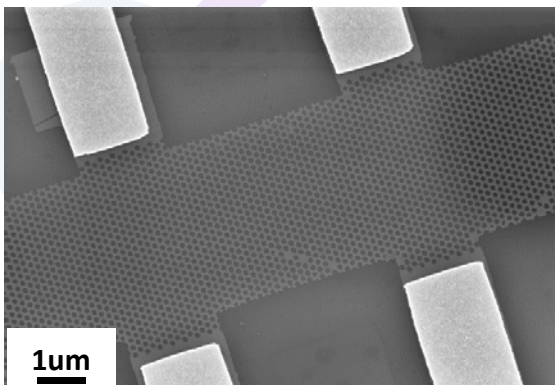
Raith i_LiNE

- Ion beam lithography
- Focused ion beam milling
- Direct write insulator and metal patterns
- Precise patterning without imaging



Application Examples

1. Graphene nanostructure modified by e_LiNE



2. Magnetic plasmonic structure fabricated by i_LiNE

